



| <b>INFORMATION DISCLOSURE<br/>CITATION IN AN<br/>APPLICATION<br/>(PTO-1449)</b> |            |          |                                    | <b>ATTY. DOCKET NO.</b><br>008089 USA/MTCG/PCTRL |          | <b>SERIAL NO.</b><br>10/809,906 |  |
|---|------------|----------|------------------------------------|--|----------|---------------------------------|--|
|   |            |          |                                    | <b>APPLICANT</b><br>Rahul SURANA et al.          |          |                                 |  |
|   |            |          |                                    | <b>FILING DATE</b><br>March 26, 2004             |          | <b>GROUP</b>                    |  |
| <b>U.S. PATENT DOCUMENTS</b>  |            |          |                                    |  |          |                                 |  |
| EXAMINER'S<br>INITIALS  | PATENT NO. | DATE     | NAME                               | CLASS  | SUBCLASS | FILING<br>DATE                  |  |
| SLW   | 3,205,485  | 09/07/65 | Noltingk                           |  |          | 10/21/60                        |  |
|   | 3,229,198  | 01/11/66 | Libby                              |  |          | 09/28/62                        |  |
|   | 3,767,900  | 10/23/73 | Chao et al.                        |  |          | 06/23/71                        |  |
|   | 3,920,965  | 11/18/75 | Sohrwardy                          |  |          | 03/04/74                        |  |
|   | 4,000,458  | 12/28/76 | Miller et al.                      |  |          | 08/21/75                        |  |
|   | 4,207,520  | 06/10/80 | Flora et al.                       |  |          | 04/06/78                        |  |
|   | 4,209,744  | 06/24/80 | Gerasimov et al.                   |  |          | 03/27/78                        |  |
|   | 4,302,721  | 11/24/81 | Urbanek et al.                     |  |          | 05/15/79                        |  |
|   | 4,368,510  | 01/11/83 | Anderson                           |  |          | 10/20/80                        |  |
|   | 4,609,870  | 09/02/86 | Lale et al.                        |  |          | 09/13/84                        |  |
|   | 4,616,308  | 10/07/86 | Morshedi et al.                    |  |          | 12/02/85                        |  |
|   | 4,663,703  | 05/05/87 | Axelby et al.                      |  |          | 10/02/85                        |  |
|   | 4,698,766  | 10/06/87 | Entwistle et al.                   |  |          | 05/17/85                        |  |
|   | 4,750,141  | 06/07/88 | Judell et al.                      |  |          | 11/26/85                        |  |
|   | 4,755,753  | 07/05/88 | Chern                              |  |          | 07/23/86                        |  |
|   | 4,757,259  | 07/12/88 | Charpentier                        |  |          | 11/05/86                        |  |
|   | 4,796,194  | 01/03/89 | Atherton                           |  |          | 08/20/86                        |  |
|   | 4,901,218  | 02/13/90 | Cornwell                           |  |          | 03/04/88                        |  |
|   | 4,938,600  | 07/03/90 | Into                               |  |          | 02/09/89                        |  |
|   | 4,967,381  | 10/30/90 | Lane et al.                        |  |          | 07/06/89                        |  |
|   | 5,089,970  | 02/18/92 | Lee et al.                         |  |          | 10/05/89                        |  |
|   | 5,108,570  | 04/28/92 | Wang                               |  |          | 03/30/90                        |  |
|   | 5,208,765  | 05/04/93 | Turnbull                           |  |          | 07/20/90                        |  |
|   | 5,220,517  | 06/15/93 | Sierk et al.                       |  |          | 08/31/90                        |  |
|   | 5,226,118  | 07/06/93 | Baker et al.                       |  |          | 01/29/91                        |  |
|   | 5,231,585  | 07/27/93 | Kobayashi et al.                   |  |          | 06/20/90                        |  |
|   | 5,236,868  | 08/17/93 | Nulman                             |  |          | 04/20/90                        |  |
| SLW   | 5,260,868  | 11/09/93 | Gupta et al.                       |  |          | 10/15/91                        |  |
| <b>EXAMINER</b><br>Shantanu Acharya   |            |          | <b>DATE CONSIDERED</b><br>12/12/05 |  |          |                                 |  |

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|   |            |          |                             | APPLICANT<br>Rahul SURANA et al.          |          |                          |  |
|   |            |          |                             | FILING DATE<br>March 26, 2004             |          | GROUP                    |  |
| <b>U.S. PATENT DOCUMENTS</b>  |            |          |                             |   |          |                          |  |
| EXAMINER'S<br>INITIALS  | PATENT NO. | DATE     | NAME                        | CLASS                                     | SUBCLASS | FILING<br>DATE           |  |
| SUM   | 5,270,222  | 12/14/93 | Moslehi                     |   |          | 12/31/90                 |  |
|   | 5,283,141  | 02/01/94 | Yoon et al.                 |   |          | 03/05/92                 |  |
|   | 5,295,242  | 03/15/94 | Mashruwala et al.           |   |          | 11/02/90                 |  |
|   | 5,309,221  | 05/03/94 | Fischer et al.              |   |          | 12/31/91                 |  |
|   | 5,329,463  | 07/12/94 | Sierk et al.                |   |          | 01/13/93                 |  |
|   | 5,338,630  | 08/16/94 | Yoon et al.                 |   |          | 11/18/93                 |  |
|   | 5,347,446  | 09/13/94 | Iino et al.                 |   |          | 02/10/92                 |  |
|   | 5,367,624  | 11/22/94 | Cooper                      |   |          | 06/11/93                 |  |
|   | 5,375,064  | 12/20/94 | Bollinger                   |   |          | 12/02/93                 |  |
|   | 5,398,336  | 03/14/95 | Tantry et al.               |   |          | 06/16/93                 |  |
|   | 5,402,367  | 03/28/95 | Sullivan et al.             |   |          | 07/19/93                 |  |
|   | 5,408,405  | 04/18/95 | Mozumder et al.             |   |          | 09/20/93                 |  |
|   | 5,410,473  | 04/25/95 | Kaneko et al.               |   |          | 12/16/92                 |  |
|   | 5,420,796  | 05/30/95 | Weling et al.               |   |          | 12/23/93                 |  |
|   | 5,427,878  | 06/27/95 | Corliss                     |   |          | 05/16/94                 |  |
|   | 5,469,361  | 11/21/95 | Moyne                       |   |          | 06/06/94                 |  |
|   | 5,485,082  | 01/16/96 | Wisspeintner et al.         |   |          | 04/05/90                 |  |
|   | 5,490,097  | 02/06/96 | Swenson et al.              |   |          | 08/06/93                 |  |
|   | 5,495,417  | 02/27/96 | Fuduka et al.               |   |          | 03/16/93                 |  |
|   | 5,497,316  | 03/05/96 | Sierk et al.                |   |          | 04/04/95                 |  |
|   | 5,497,381  | 03/05/96 | O'Donoghue et al.           |   |          | 06/01/95                 |  |
|   | 5,503,707  | 04/02/96 | Maung et al.                |   |          | 09/22/93                 |  |
|   | 5,508,947  | 04/16/96 | Sierk et al.                |   |          | 05/13/94                 |  |
|   | 5,511,005  | 04/23/96 | Abbe et al.                 |   |          | 02/16/94                 |  |
|   | 5,519,605  | 05/21/96 | Cawfield                    |   |          | 10/24/94                 |  |
|   | 5,525,808  | 06/11/96 | Irie et al.                 |   |          | 12/20/94                 |  |
|   | 5,526,293  | 06/11/96 | Mozumder et al.             |   |          | 12/17/93                 |  |
|   | 5,534,289  | 07/09/96 | Bilder et al.               |   |          | 01/03/95                 |  |
| SUM   | 5,541,510  | 07/30/96 | Danielson                   |   |          | 04/06/95                 |  |
| EXAMINER<br><i>Shantae de S...</i>  |            |          | DATE CONSIDERED<br>12/12/05 |   |          |                          |  |

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| <b>U.S. PATENT DOCUMENTS</b>  |            |          |                     |   |          |                          |  |
| EXAMINER'S<br>INITIALS  | PATENT NO. | DATE     | NAME                | CLASS                                     | SUBCLASS | FILING<br>DATE           |  |
| SLM   | 5,546,312  | 08/13/96 | Mozumder et al.     |   |          | 02/24/94                 |  |
|   | 5,553,195  | 09/03/96 | Meijer              |   |          | 09/29/94                 |  |
|   | 5,586,039  | 12/17/96 | Hirsch et al.       |   |          | 02/27/95                 |  |
|   | 5,599,423  | 02/04/97 | Parker et al.       |   |          | 06/30/95                 |  |
|   | 5,602,492  | 02/11/97 | Cresswell et al.    |   |          | 04/28/94                 |  |
|   | 5,603,707  | 02/18/97 | Trombetta et al.    |   |          | 11/28/95                 |  |
|   | 5,617,023  | 04/01/97 | Skalski             |   |          | 02/02/95                 |  |
|   | 5,627,083  | 05/06/97 | Tounai              |   |          | 05/12/95                 |  |
|   | 5,629,216  | 05/13/97 | Wijaranakula et al. |   |          | 02/27/96                 |  |
|   | 5,642,296  | 06/24/97 | Saxena              |   |          | 07/29/93                 |  |
|   | 5,646,870  | 07/08/97 | Krivokapic et al.   |   |          | 02/13/95                 |  |
|   | 5,649,169  | 07/15/97 | Berezin et al.      |   |          | 06/20/95                 |  |
|   | 5,654,903  | 08/05/97 | Reitman et al.      |   |          | 11/07/95                 |  |
|   | 5,655,951  | 08/12/97 | Meikle et al.       |   |          | 09/29/95                 |  |
|   | 5,657,254  | 08/12/97 | Sierk et al.        |   |          | 04/15/96                 |  |
|   | 5,661,669  | 08/26/97 | Mozumder et al.     |   |          | 06/07/95                 |  |
|   | 5,663,797  | 09/02/97 | Sandhu              |   |          | 05/16/96                 |  |
|   | 5,664,987  | 09/09/97 | Renteln             |   |          | 09/04/96                 |  |
|   | 5,665,199  | 09/09/97 | Sahota et al.       |   |          | 06/23/95                 |  |
|   | 5,666,297  | 09/09/97 | Britt et al.        |   |          | 05/13/94                 |  |
|   | 5,667,424  | 09/16/97 | Pan                 |   |          | 09/25/96                 |  |
|   | 5,674,787  | 10/07/97 | Zhao et al.         |   |          | 01/16/96                 |  |
|   | 5,694,325  | 12/02/97 | Fukuda et al.       |   |          | 11/22/95                 |  |
|   | 5,698,989  | 12/16/97 | Nulman              |   |          | 09/13/96                 |  |
|   | 5,719,495  | 02/17/98 | Moslehi             |   |          | 06/05/96                 |  |
|   | 5,719,796  | 02/17/98 | Chen                |   |          | 12/04/95                 |  |
|   | 5,735,055  | 04/07/98 | Hochbein et al.     |   |          | 04/23/96                 |  |
| SLM   | 5,740,429  | 04/14/98 | Wang et al.         |   |          | 07/07/95                 |  |
| EXAMINER<br><i>S. Hunter</i>  |            |          |                     | DATE CONSIDERED<br>12/12/05               |          |                          |  |

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| EXAMINER'S<br>INITIALS  | PATENT NO. | DATE     | NAME                        | CLASS                                     | SUBCLASS | FILING<br>DATE           |  |
| SLW   | 5,751,582  | 05/12/98 | Saxena et al.               |   |          | 09/24/96                 |  |
|   | 5,754,297  | 05/19/98 | Nulman                      |   |          | 04/14/97                 |  |
|   | 5,761,064  | 06/02/98 | La et al.                   |   |          | 10/06/95                 |  |
|   | 5,761,065  | 06/02/98 | Kittler et al.              |   |          | 03/30/95                 |  |
|   | 5,764,543  | 06/09/98 | Kennedy                     |   |          | 06/16/95                 |  |
|   | 5,777,901  | 07/07/98 | Berezin et al.              |   |          | 09/29/95                 |  |
|   | 5,787,021  | 07/28/98 | Samaha                      |   |          | 12/18/95                 |  |
|   | 5,787,269  | 07/28/98 | Hyodo                       |   |          | 09/19/95                 |  |
|   | 5,808,303  | 09/15/98 | Schlagheck et al.           |   |          | 01/29/97                 |  |
|   | 5,812,407  | 09/22/98 | Sato et al.                 |   |          | 08/12/97                 |  |
|   | 5,823,854  | 10/20/98 | Chen                        |   |          | 05/28/96                 |  |
|   | 5,825,913  | 10/20/98 | Rostami et al.              |   |          | 07/18/95                 |  |
|   | 5,828,778  | 10/27/98 | Hagi et al.                 |   |          | 07/12/96                 |  |
|   | 5,832,224  | 11/03/98 | Fehskens et al.             |   |          | 06/14/96                 |  |
|   | 5,838,595  | 11/17/98 | Sullivan et al.             |   |          | 11/25/96                 |  |
|   | 5,844,554  | 12/01/98 | Geller et al.               |   |          | 09/17/96                 |  |
|   | 5,857,258  | 01/12/99 | Penzes et al.               |   |          | 05/12/94                 |  |
|   | 5,859,964  | 01/12/99 | Wang et al.                 |   |          | 10/25/96                 |  |
|   | 5,859,975  | 01/12/99 | Brewer et al.               |   |          | 08/09/96                 |  |
|   | 5,862,054  | 01/19/99 | Li                          |   |          | 02/20/97                 |  |
|   | 5,863,807  | 01/26/99 | Jang et al.                 |   |          | 03/15/96                 |  |
|   | 5,867,389  | 02/02/99 | Hamada et al.               |   |          | 11/26/96                 |  |
|   | 5,870,306  | 02/09/99 | Harada                      |   |          | 06/13/97                 |  |
|   | 5,883,437  | 03/16/99 | Maruyama et al.             |   |          | 12/28/95                 |  |
|   | 5,889,991  | 03/30/99 | Consolatti et al.           |   |          | 12/06/96                 |  |
|   | 5,901,313  | 05/04/99 | Wolfe et al.                |   |          | 09/02/97                 |  |
|   | 5,903,455  | 05/11/99 | Sharpe, Jr. et al.          |   |          | 12/12/96                 |  |
|   | 5,910,011  | 06/08/99 | Cruse                       |   |          | 05/12/97                 |  |
| SLW   | 5,910,846  | 06/08/99 | Sandhu                      |   |          | 08/19/97                 |  |
| EXAMINER<br><i>Shantze Anderson</i>   |            |          | DATE CONSIDERED<br>12/12/05 |   |          |                          |  |

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| EXAMINER'S<br>INITIALS  | PATENT NO.   | DATE     | NAME             | CLASS                                     | SUBCLASS | FILING<br>DATE           |  |
| SM  | 6,127,263    | 10/03/00 | Parikh           |   |          | 07/10/98                 |  |
|   | 6,128,016    | 10/03/00 | Coelho et al.    |   |          | 12/20/96                 |  |
|   | 6,136,163    | 10/24/00 | Cheung et al.    |   |          | 03/05/99                 |  |
|   | 6,141,660    | 10/31/00 | Bach et al.      |   |          | 07/16/98                 |  |
|   | 6,143,646    | 11/07/00 | Wetzel           |   |          | 06/03/97                 |  |
|   | 6,148,099    | 11/14/00 | Lee et al.       |   |          | 07/03/97                 |  |
|   | 6,148,239    | 11/14/00 | Funk et al.      |   |          | 12/12/97                 |  |
|   | 6,148,246    | 11/14/00 | Kawazome         |   |          | 06/10/98                 |  |
|   | 6,150,664    | 11/21/00 | Su               |   |          | 06/29/99                 |  |
|   | 6,159,644    | 12/12/00 | Satoh et al.     |   |          | 03/06/96                 |  |
|   | 6,161,054 B1 | 12/12/00 | Rosenthal et al. |   |          | 09/17/98                 |  |
|   | 6,169,931 B1 | 01/02/01 | Runnels          |   |          | 07/29/98                 |  |
|   | 6,172,756 B1 | 01/09/01 | Chalmers et al.  |   |          | 12/11/98                 |  |
|   | 6,173,240 B1 | 01/09/01 | Sepulveda et al. |   |          | 11/02/98                 |  |
|   | 6,175,777 B1 | 01/16/01 | Kim              |   |          | 01/16/98                 |  |
|   | 6,178,390 B1 | 01/23/01 | Jun              |   |          | 09/08/98                 |  |
|   | 6,183,345 B1 | 02/06/01 | Kamono et al.    |   |          | 03/20/98                 |  |
|   | 6,185,324 B1 | 02/06/01 | Ishihara et al.  |   |          | 01/31/95                 |  |
|   | 6,191,864 B1 | 02/20/01 | Sandhu           |   |          | 02/29/00                 |  |
|   | 6,192,291 B1 | 02/20/01 | Kwon             |   |          | 10/08/98                 |  |
|   | 6,197,604 B1 | 03/06/01 | Miller et al.    |   |          | 10/01/98                 |  |
|   | 6,204,165 B1 | 03/20/01 | Ghoshal          |   |          | 06/24/99                 |  |
|   | 6,210,983 B1 | 04/03/01 | Atchison et al.  |   |          | 06/15/99                 |  |
|   | 6,211,094 B1 | 04/03/01 | Jun et al.       |   |          | 08/23/99                 |  |
|   | 6,214,734 B1 | 04/10/01 | Bothra et al.    |   |          | 11/20/98                 |  |
| SM  | 6,219,711 B1 | 04/17/01 | Chari            |   |          | 10/01/97                 |  |
| EXAMINER<br><i>Shantane Desai</i>   |              |          |                  | DATE CONSIDERED<br>12/12/05               |          |                          |  |

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| EXAMINER'S<br>INITIALS  | PATENT NO.                          | DATE         | NAME             | CLASS                                     | SUBCLASS                    | FILING<br>DATE           |          |  |
| <i>Sum</i>  | 6,226,792 B1                        | 05/01/01     | Goiffon et al.   |   |                             | 10/14/98                 |          |  |
|   | 6,230,069 B1                        | 05/08/01     | Campbell et al.  |   |                             | 06/26/98                 |          |  |
|   | 6,236,903 B1                        | 05/22/01     | Kim et al.       |   |                             | 09/25/98                 |          |  |
|   | 2001/0001755 A1                     | 05/24/01     | Sandhu et al.    |   |                             | 12/29/00                 |          |  |
|   | 6,240,330 B1                        | 05/29/01     | Kurtzberg et al. |   |                             | 05/28/97                 |          |  |
|   | 6,240,331 B1                        | 05/29/01     | Yun              |   |                             | 08/18/98                 |          |  |
|   | 6,245,581 B1                        | 06/12/01     | Bonser et al.    |   |                             | 04/19/00                 |          |  |
|   | 6,246,972 B1                        | 06/12/01     | Klimasauskas     |   |                             | 05/27/99                 |          |  |
|   | 6,248,602 B1                        | 06/19/01     | Bode et al.      |   |                             | 11/01/99                 |          |  |
|   | 6,249,712 B1                        | 06/19/01     | Boiquaye         |   |                             | 09/25/96                 |          |  |
|   | 6,252,412 B1                        | 06/26/01     | Talbot et al.    |   |                             | 01/08/99                 |          |  |
|   | 6,253,366 B1                        | 06/26/01     | Mutschler, III   |   |                             | 03/31/99                 |          |  |
|   | 6,263,255 B1                        | 07/17/01     | Tan et al.       |   |                             | 05/18/98                 |          |  |
|   | 6,271,670 B1                        | 08/07/01     | Caffey           |   |                             | 02/08/99                 |          |  |
|   | 6,276,989 B1                        | 08/21/01     | Campbell et al.  |   |                             | 08/11/99                 |          |  |
|   | 6,278,899 B1                        | 08/21/01     | Piche et al.     |   |                             | 10/06/98                 |          |  |
|   | 6,284,622 B1                        | 09/04/01     | Campbell et al.  |   |                             | 10/25/99                 |          |  |
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|   | 6,290,572 B1                        | 09/18/01     | Hofmann          |   |                             | 03/23/00                 |          |  |
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|   |  |              |                   | <b>APPLICANT</b><br>Rahul SURANA et al.          |   |                                 |          |  |
|   |  |              |                   | <b>FILING DATE</b><br>March 26, 2004             |   | <b>GROUP</b>                    |          |  |
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| <i>Sup</i>             | 61-66104        | 04/04/86 | Japan   |       |          | X           |    |
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*Shantane Keshane*

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|   |                 |          |         | APPLICANT<br>Rahul SURANA et al.          |          |                          |    |
|   |                 |          |         | FILING DATE<br>March 26, 2004             |          | GROUP                    |    |
| <b>FOREIGN PATENT DOCUMENTS</b>   |                 |          |         |   |          |                          |    |
| EXAMINER'S<br>INITIALS  | PATENT NO.      | DATE     | COUNTRY | CLASS                                     | SUBCLASS | Translation              |    |
|   |                 |          |         |   |          | Yes                      | No |
| Sum   | 2001-76982      | 03/23/01 | Japan   |   |          | X                        |    |
|   | WO 01/25865 A1  | 04/12/01 | WO      |   |          | X                        |    |
|   | EP 1 092 505 A2 | 04/18/01 | Europe  |   |          | X                        |    |
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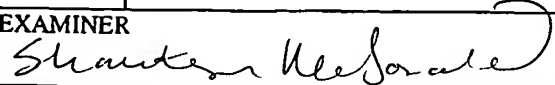
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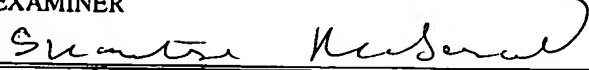
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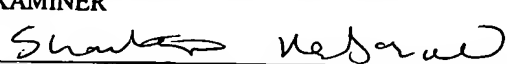
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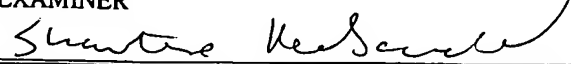
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## INFORMATION DISCLOSURE CITATION IN AN APPLICATION

(PTO-1449)



ATTY. DOCKET NO.  
008089 USA/  
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**SERIAL NO.**  
**10/809,906**

**APPLICANT**  
**Rahul SURANA et al.**

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| <b>EXAMINER</b><br>Shawter (Referred)   |              |              | <b>DATE CONSIDERED</b><br>12/2/05 |  |          |                                 |          |  |

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|  |                 |          |                             | APPLICANT<br>Rahul SURANA et al.              |          |                          |  |
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|   |                 |          |                        | FILING DATE<br>March 26, 2004                 |          | GROUP                    |  |
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| <b>FOREIGN PATENT DOCUMENTS</b>   |   |          |         |   |          |                          |    |
| EXAMINER'S<br>INITIALS  | PATENT NO.  | DATE     | COUNTRY | CLASS   | SUBCLASS | Translation              |    |
|   |   |          |         |   |          | Yes                      | No |
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